BEAMLINE	SCIENTIFIC TOPIC	ENERGY RANGE *keV*	BEAM SIZE *H x V*	NOMINAL FLUX *ph/sec*	DETECTORS	SAMPLE ENVIRONMENT *& Beamline Support Labs*	TECHNIQUE
BM32 *IF (French Interface Beamline)* SCIENTIST IN CHARGE **Jean Sebastien Micha** micha@esrf.fr	Chemistry Env. Sciences & Geosciences Materials Processing Physics	5 - 30	**Microdiffraction laue** **MIN** 0.5 x 0.7 μm^2 **Standard monochromatic** **MAX** 500 x 300 μm^2	**Microdiffraction laue** 10^6 -10^7 *0,015%E* **Standard monochromatic** 5 x 10^{11}	**INS** ▪ 2D detector **GMT** ▪ 0D: NaI scintillation detector ▪ 2D: CCD camera Photonics Science ImageStar, 1 sCMOS ▪ Rectangular pixel detector ESRF MaxiPix 2 Si 1 CdTe	**INS** ▪ High temperature furnace (max. 1000°C) ▪ MBE chamber, CBE (gas injection), Auger, RHEED, surface preparation **GMT** ▪ Mechanical test machine ▪ Furnace in vacuum chamber (25 - 900°C) ▪ Circulating bath (-10 - 70°C) **Beamline Support labs** ▪ Electronic and mechanical workshop ▪ UHV sample preparation lab	Diffraction Scattering